

Title (en)
METHOD AND DEVICE FOR CHANGING TEST SUBSTRATES IN A CONTINUOUS-FLOW VACUUM SYSTEM, TREATMENT METHOD, AND CONTINUOUS-FLOW VACUUM SYSTEM

Title (de)
VERFAHREN UND VORRICHTUNG ZUM WECHSEL VON TESTSUBSTRATEN IN EINER VAKUUMDURCHLAUFANLAGE, BEHANDLUNGSVERFAHREN UND VAKUUMDURCHLAUFANLAGE

Title (fr)
PROCÉDÉ ET DISPOSITIF POUR CHANGER DES SUBSTRATS D'ESSAI DANS UN SYSTÈME DE PASSAGE SOUS VIDE, PROCÉDÉ DE TRAITEMENT, ET INSTALLATION DE PASSAGE SOUS VIDE

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Abstract (en)
[origin: WO2022128026A1] The invention relates to a method for changing test substrates in a continuous-flow vacuum system in the course of a multiple-treatment-step process cycle for treating a substrate. For at least two treatment steps, at least two test substrates (66) are transferred to the vacuum treatment system at the beginning of the process cycle and are transferred back out of it once the process cycle is concluded. After the first treatment step, the first test substrate (66) concurrently treated in this step is removed from the measurement position (70) it occupied during the treatment and is deposited in an empty position (71) without a test substrate (66). Subsequently, the second test substrate (66) which has not been treated yet is deposited in the resulting free measurement position (70) for the purpose of supplying the second test substrate to the subsequent treatment step of the substrates (61). The invention likewise relates to a treatment method which uses the method and to systems for treating a plurality of substrates (61) and for changing test substrates.

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